



IFW

Docket No.: 070759-0042

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
Yasuhiro WATANABE, et al.	:	Confirmation Number: 4678
Application No.: 10/575,899	:	Group Art Unit: 2814
Filed: April 14, 2006	:	Examiner: Long Pham
For: SEMICONDUCTOR LASER DEVICE AND MANUFACTURING METHOD THEREOF		

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

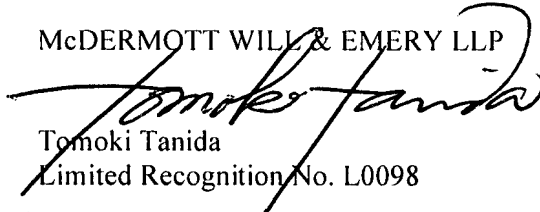
Sir:

Noting the Office Action of March 9, 2007 wherein restriction has been required, Applicant hereby elects Group I (claims 11-14) for prosecution in the above-identified application.¹

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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**Please recognize our Customer No. 20277 as
our correspondence address.**

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¹ The March 9, 2007 Office Action has required Applicant to elect Group I (claims 11-13 drawn to a semiconductor device) or Group II (claims 14-16 drawing to a semiconductor process). However, claim 14 is directed to a semiconductor device. Applicant presumes that the Examiner intended to mention in the Office Action that Group I includes claims 11-14 and Group II includes claims 15 and 16.